

## IN THE CLAIMS

Please add the following claims.

63. (New) A plasma-generation system, comprising:

a first plasma chamber;

a second plasma chamber having a deposition mode and a cleaning mode, wherein said second plasma chamber comprises:

a housing defining a process area and coupled to said first plasma chamber, and

a plasma inducer around said housing; and

a conductive material present after said deposition mode between said process area and said inducer.

64. (New) The system in claim 63, wherein said conductive material is between said process area and said housing.

65. (New) The (method) in claim 64, wherein said conductive material is absent after said cleaning mode.

66. (New) The (method) in claim 65, wherein said conductive material is absent before said deposition mode.

67. (New) A furnace assembly, comprising:

a first material that is opaque to a type of energy;

a structure defining a furnace interior, wherein at least a part of said structure is

transparent to said energy, wherein said part contacts said first material, and

wherein said structure is configured to interpose between a source of said energy and said first material; and

a plasma delivery system in fluid communication with said interior defined by said structure.

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